



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: William D. Sawyer, et al.
Serial No.: 10/642,315
Filed: August 15, 2003
Title: Method for Microfabricating Structures Using Silicon-On-Insulator Material
Docket: CSLL-662CP (56247-235)

CERTIFICATE OF MAILING (37 C.F.R. § 1.8(a))

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Date: 4-26-2005

Weiguo Chen

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Sir:

RESPONSE

In response to the Office Action dated January 26, 2005, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper; and

Remarks/Arguments begin on page 6 of this paper.